

PROCEEDINGS OF SPIE

Advances in Thin-Film Coatings for Optical Applications V

**Jennifer D. T. Kruschwitz
Michael J. Ellison**
Editors

**11 August 2008
San Diego, California, USA**

Sponsored and Published by
SPIE

Volume 7067

Proceedings of SPIE, 0277-786X, v. 7067

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Advances in Thin-Film Coatings for Optical Applications V, edited by Jennifer D. T. Kruschwitz,
Michael J. Ellison, Proc. of SPIE Vol. 7067, 706701, (2008)
0277-786X/08/\$18 · doi: 10.1117/12.812909

Proc. of SPIE Vol. 7067 706701-1

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Author(s), "Title of Paper," in *Advances in Thin-Film Coatings for Optical Applications V*, edited by Jennifer D. T. Kruschwitz, Michael J. Ellison, Proceedings of SPIE Vol. 7067 (SPIE, Bellingham, WA, 2008) Article CID Number.

ISSN 0277-786X
ISBN 9780819472878

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org

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